



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
United States Patent and Trademark Office
Address: COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450
www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/517,345	03/02/2000	Sidney Larry Anderson	15114-052310	4253
26059	7590	03/15/2005	EXAMINER	
TOWNSEND AND TOWNSEND AND CREW LLP/ 015114			PAREKH, NITIN	
TWO EMBARCADERO CENTER			ART UNIT	
8TH FLOOR			PAPER NUMBER	
SAN FRANCISCO, CA 94111-3834			2811	

DATE MAILED: 03/15/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary	Application No. ✓ 09/517,345	Applicant(s) ANDERSON ET AL.	
	Examiner Nitin Parekh	Art Unit 2811	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 12 November 2004.
- 2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1,2,4,6-25,49-64 and 66-70 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1,2,4,6-25,49-64 and 66-69 is/are rejected.
- 7) ☒ Claim(s) 70 is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 24 March 2004 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- * See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Claim Objections

1. Claim 70 is objected to because of the following informalities:
 - A. Claim 70 should be cancelled because claim 70 depends on claim 3, which is cancelled.

Appropriate correction is required.

Claim Rejections - 35 USC § 103

2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

3. Claims 1, 2, 4 and 6-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) in view of Zenner et al. (US Pat. 6246010), Freyman et al. (US Pat. 5985695) and Lau (see "Chip on Board Technologies for Multichip Modules" edited by John H. Lau, published by Chapman & Hall, 1994).

Regarding claims 1, 10 and 11, Schueller discloses an integrated circuit (IC)/BGA package comprising:

- a silicon die (52 in Fig. 3A) having a first thickness
- a metallized polymer layer/flexible dielectric tape substrate (59/60 in Fig. 3A; Col. 7, line 30) having a first/top side and a second/bottom side, and
- a transition medium/support structure (50 in Fig. 3A) disposed between the silicon die and the first side of the metallized polymer layer where the transition medium/support structure has a second thickness
- the die being coupled to the transition medium through an adhesive (64 in Fig. 3A; Col. 9, line 65), and
- a plastic encapsulant/mold cap encapsulating the transition medium and the die (mold cap not numerically referenced in Fig. 3A; see 86 in Col. 8, line 40)

(Fig. 3A; Col. 7, line 15- Col. 10, line 36; Col. 5, line 36- Col. 6, line 55).

Schueller further teaches using a single transition medium/support structure having a second thickness/layer of 100-250 microns (Col. 9, line 49) or using a plurality of those layers (Col. 11, line 12) and the transition medium/support structure comprising a variety of material including conventional PCB/FR-4/epoxy resin (Col. 10, lines 18-28), an adhesive, an elastomer, etc. (see 224 in Fig. 2 and 10 in Fig. 1; Col. 5, line 42; Col. 6, line 44; Col. 5 and 6).

Schueller fails to teach:

- a) the first thickness of the silicon die being less than the second thickness, and
- b) a first and a second edge of the transition medium being coincident with those of the silicon die respectively, and
- c) the encapsulant and the transition medium each having a coefficient of thermal expansion (CTE) approximately between $7-15 \times 10^{-6}/^{\circ}\text{C}$.

a) Zenner et al. teach using a high density/thin package having a die thickness/first thickness where the die has been thinned/lapped to about less than 100 microns or preferably less than 20 microns and a package thickness of about 275 microns (Col. 2, line 15-22; Col. 3, line 55; Col. 2-4) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

b) Freyman et al. teach a BGA package (Fig. 7) having dimensions of a flexible substrate, an adhesive medium/transition and a die (201, 703 and 41 respectively in Fig. 7) such that a first and a second edge of the adhesive medium/transition medium are coincident with those of the die (see 703 and 41 respectively in Fig. 7; Col. 9, lines 1-5).

C) Lau teaches conventional material including a PCB/epoxy resin having a CTE ranging from $5-19 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 52, Table 1-7), an epoxy encapsulant/mold compound having that from $10-15 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 474-476), and a conventional adhesive/silicone material having that from $50-150 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 507, Table 12-2).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate elements a)-c) and the adhesive having the CTE of approximately $58 \times 10^{-6}/^{\circ}\text{C}$ as taught by Zenner et al., Freyman et al. and Lau so that the thermal stress can be reduced, the functionality/reliability can be improved and processing can be simplified in Schueller's IC package.

Regarding claims 2 and 6, Schueller, Zenner et al., Freyman et al. and Lau teach substantially the entire claimed structure as applied to claim 1 above, wherein Schueller further teaches the transition medium/support structure comprising a single or multilayered structure including conventional conductive/non-conductive material such as ceramic, metal, PCB or a combination of metal and non-metal/epoxy PCB material (Col. 9, line 58; Col. 10, line 27; Col. 11, line 12). Furthermore, Schueller discloses selecting the transition medium/support structure to provide various functions such as improved strength (Col. 9, line 52), thermal dissipation (Col. 9, line 10), etc. so that the thermal stress and defects such as fracture, cracking, etc. can be reduced (Col. 6-10).

Regarding claims 4 and 70, Schueller, Zenner et al., Freyman et al. and Lau teach substantially the entire claimed structure as applied to claim 1 above, wherein Schueller teaches the transition medium/support structure comprising the epoxy material, being same as that of the plastic encapsulant/epoxy mold material having approximately similar/equal CTE (Col. 10, line 18-27).

Regarding claim 7, Schueller, Zenner et al., Freyman et al. And Lau teach substantially the entire claimed structure as applied to claim 1 above, wherein Schueller further

teaches the die being disposed approximately near the middle of a package having a thickness where the package thickness is defined by the thickness of the metallized polymer layer/tape and that of the plastic encapsulant/mold cap (Col. 8, line 40; Fig. 3A), but fail to teach the die being disposed approximately equally spaced from the bottom of the metallized polymer layer and the top of the plastic encapsulant.

The determination of parameters such as a thickness of a substrate/metallized polymer, plastic encapsulant/mold, finished package including the die, substrate and the encapsulant, thickness/area/volume ratio of various components, relative position and an arrangement of various components within the package, etc. in the chip packaging and encapsulation technology art is a subject of routine experimentation and optimization to achieve the desired thermal, dimensional/mechanical and electrical/reliability requirements including weight/size, rigidity/strength and stress distribution.

It would have been obvious to a person of ordinary skill in the art at the time invention was made to select the thickness of the encapsulant such that die is disposed approximately equally spaced from the bottom of the metallized polymer layer and the top of the plastic encapsulant so that the desired thermal/mechanical stress can be reduced and the and the reliability of the package can be improved in Lau, Freyman et al., Zenner et al. and Schueller's IC package.

Regarding claims 8 and 9, Schueller, Zenner et al., Freyman et al. and Lau teach substantially the entire claimed structure as applied to claims 1, 5 and 7 above, except the thickness of the package and die being 0.06 inches/60 mils or less and 6 mils and less respectively.

Zenner et al. further teach using the high density/thin package having the die thickness of about less than 100 microns/4 mils and a package thickness of about 275 microns/11 mils (Col. 2, line 15-22; Col. 3, line 55) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to select the thickness of the package and the die to be less than approximately 0.060 inches and 6 mils respectively as taught by Zenner et al. so that the desired thermal/mechanical stress can be reduced and the reliability of the package can be improved in Lau, Freyman et al., Zenner et al. Schueller's IC package.

Regarding claims 10 and 11, Schueller, Zenner et al., Freyman et al., and Lau teach substantially the entire claimed structure as applied to claim 1, above, wherein Schueller further teaches the die being coupled to the transition medium through an adhesive (64 in Fig. 3A; Col. 9, line 65).

Regarding claims 12 and 13, Schueller, Freyman et al., Zenner et al. and Lau teach substantially the entire claimed structure as applied to claim 1, above, wherein Schueller further teaches the metallized polymer layer/flexible dielectric tape having conventional dielectric and conductive layers (60 and 59 respectively in Fig. 3A; Col. 7) and solder balls being mounted to the second side of the metallized polymer layer and electrically contacting the etched circuit in a conductive layer of the tape carrier (Fig. 3B; Col. 7, lines 32 and 58; Col. 5-12; Fig. 6).

Regarding claims 14 and 15, Schueller, Zenner et al. Freyman et al. and Lau teach substantially the entire claimed structure as applied to claims 1, 12 and 13 above, wherein Schueller further teaches the solder balls being arranged in a grid fashion under the position for the silicon die (Fig. 3B; Col. 7, lines 32 and 58; Col. 5-12; Fig. 6) and electrically connecting the package to a PCB (Fig. 3B; Col. 7, lines 32 and 58; Col. 5-12; Fig. 6).

Regarding claims 16 and 17, Schueller, Zenner et al., Freyman et al. and Lau teach substantially the entire claimed structure as applied to claim 1, above, wherein Schueller further teaches a variety of configurations (see Fig. 3A-3D, 5 and 6) where the a cross-sectional area of the die is nearly equal to or substantially less than that of the rigid transition medium (Col. 8-12) and Zenner et al. teach the die being thinned/processed/lapped to the desired first thickness (see Col. 2 and 4).

Regarding claim 18, Schueller, Zenner et al., Freyman et al. and Lau teach substantially the entire claimed structure as applied to claim 1, above, wherein Schueller teaches the package being the BGA package.

Regarding claim 19, Schueller, Zenner et al., Freyman et al. and Lau teach substantially the entire claimed structure as applied to claim 1, above, but fail to teach die having a volume being less than that of the rigid transition medium.

As explained above, Schueller teaches the thickness of the transition medium being 100-250 microns (Col. 9, line 49) and the cross-sectional area of the die being less than that of the rigid transition medium (Fig. 3A-3D; Col. 8-12).

Zenner et al. teach using a high density/thin package having the die thickness of about less than 100 microns or preferably less than 20 microns (Col. 2, line 15-22; Col. 3, line 55) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to select the die having a volume being less than that of the rigid transition medium as taught by Zenner et al. so that the die support and the thermal performance can be improved in Lau, Freyman et al., Zenner et al. and Schueller's IC package.

4. Claims 20-22 and 24 are rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) in view of Kimura (US Pat. 5663594).

Regarding claim 20, Schueller discloses an integrated circuit (IC)/BGA package comprising:

- a metallized polymer layer (MPL)/flexible dielectric tape (FDT) substrate (59/60 in Fig. 3A; Col. 7, lines 15-35) having a first/top side and a second/bottom side, the MPL/FDT defining a first thickness
- a transition medium/support structure (50 in Fig. 3A) coupled to the MPL/FDT, the transition medium/support structure comprising a variety of material including

conventional PCB/a first mold compound material such as an epoxy resin (Col. 10, lines 18-28)

- a silicon die (52 in Fig. 3A) coupled to the transition medium
- a conventional plastic encapsulant/a first mold compound/mold cap encapsulating the transition medium and the die (mold cap not numerically referenced in Fig. 3A; see 86 in Col. 8, line 40), the mold cap having a thickness comprising a thickness/second thickness above the transition medium, wherein the first and second thickness define a package thickness
- the die being disposed approximately in the middle of the package thickness measured from the bottom of the MPL/FDT to the top of the mold cap (see Fig. 3A), and
- solder balls (54 in Fig. 3A) and the die being electrically coupled to through respective bonding pads

(Fig. 3A; Col. 7, line 15- Col. 10, line 36; Col. 5, line 36- Col. 6, line 55).

Schueller fails to teach:

- a) dimensions of the die, transition medium and the package being such that the die is disposed near midline of the package, and
- b) at least one solder ball and metallized polymer layer comprising a flat surface.

a) The determination of parameters such as a thickness of a substrate/metallized polymer, plastic encapsulant/mold, finished package including the die, substrate and the encapsulant, thickness/area/volume ratio of various components, relative position and an arrangement of various components within the package, etc. in chip packaging and encapsulation technology art is a subject of routine experimentation and optimization to achieve the desired thermal, dimensional/mechanical and electrical/reliability requirements including weight/size, rigidity/strength and stress distribution.

b) Kimura teaches a conventional BGA package having solder ball configuration such that the solder ball (106 in Fig. 1) and metallized resin/polymer substrate (111/113/114 in Fig. 1) comprise a flat surface (see 106 and 113/114 in Fig. 1) to provide an improved adhesion and bonding (Col. 1, lines 10-51).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the elements a) and b) as taught by Freyman et al. and Kimura so that the thermal dissipation, temperature variation within the package, and stress distribution can be optimized and the surface protection for the die and the bonding/reliability can be improved in Schueller's IC package.

Regarding claim 21, Schueller and Kimura teach substantially the entire claimed structure as applied to claim 20 above, wherein Schueller teaches the mold

cap/encapsulant and the transition medium/support structure comprising the epoxy resin material having a similar CTE.

Regarding claim 22, Schueller and Kimura teach substantially the entire claimed structure as applied to claim 20 above, wherein Schueller further teaches the silicon die being coupled/mounted to the transition medium through the adhesive (64 in Fig. 3A; Col. 9, line 65).

Regarding claim 24, Schueller and Kimura teach substantially the entire claimed structure as applied to claim 20 above, wherein Schueller further teaches the metallized polymer layer being the tape carrier (59/60 in Fig. 3A; Col. 7, lines 30-35).

5. Claim 23 is rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) and Kimura (US Pat. 5663594) as applied to claim 20 above, and further in view of Freyman et al. (US Pat. 5985695).

Regarding claim 23, Schueller and Kimura teach substantially the entire claimed structure as applied to claim 20 above, except a first and a second edge of the transition medium is coincident with those of the die.

The determination of parameters such as a thickness of a substrate/metallized polymer, plastic encapsulant/mold, finished package including the die, substrate and the encapsulant, thickness/area/volume ratio of various components, relative position and an arrangement of various components within the package, etc. in chip packaging and encapsulation technology art is a subject of routine experimentation and optimization to achieve the desired thermal, dimensional/mechanical and electrical/reliability requirements including weight/size, rigidity/strength and stress distribution.

Freyman et al. teach a BGA package (Fig. 7) having dimensions of a flexible substrate, an adhesive medium/transition and a die (201, 703 and 41 respectively in Fig. 7) such that a first and a second edge of the adhesive medium/transition medium are coincident with those of the die (see 703 and 41 respectively in Fig. 7; Col. 9, lines 1-5).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the first and the second edge of the transition medium being coincident with those of the die as taught by Freymen et al. so that the thermal stress can be reduced and package dimensions and processing can be improved in Kimura and Schueller's IC package.

6. Claim 25 is rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) in view of Zenner et al (US Pat. 6246010) and Fukutomi et al. (US Pat. 5796912).

Regarding claim 25, Schueller discloses an integrated circuit (IC)/BGA package comprising:

- a metallized polymer layer (MPL)/flexible dielectric tape carrier (FDTC) substrate (59/60 in Fig. 3A; Col. 7, lines 30-35) having a first/top side and a second/bottom side, the MPL/FDT defining a first thickness
- a first adhesive layers (56 in Fig. 3A) having a thickness and a CTE disposed on the tape carrier (Fig. 3B; Col. 9, line 65; Col. 8, line 12- Col. 10, line 36)
- a transition medium/support structure (50 in Fig. 3A) having first and second surfaces where the first surface engages the first adhesive layer and the transition medium/support structure having a thickness and a CTE
- the transition medium/support structure comprising a variety of material including conventional PCB/a first mold compound material such as an epoxy resin (Col. 10, lines 18-28)
- a second adhesive layer (64 in Fig. 3A) having a thickness and a CTE disposed on the transition medium/support structure (Fig. 3A; Col. 8, line 12- Col. 10, line 36)
- a silicon die (52 in Fig. 3A) having a thickness being disposed on the second adhesive layer, and
- a conventional plastic epoxy resin/encapsulant/a first mold compound/mold cap encapsulating the first adhesive layer, transition medium, second adhesive layer and the die (mold cap not numerically referenced- see Fig. 3A; Col. 8, line 40), wherein the mold cap and the MPL/FDTC define a package thickness, and
- the thickness of the adhesive layers, transition medium and die is approximately half the package thickness (see Fig. 3A), and

- the mold cap/encapsulant/first mold compound and the transition medium/support structure/first mold compound material comprising the epoxy resin material having a similar/approximately equal CTE

(Fig. 3A; Col. 7, line 15- Col. 10, line 36; Col. 5, line 36- Col. 6, line 55).

Schueller teaches the transition medium/support and the encapsulant comprising the first mold compound/epoxy resin having approximately same CTE and further teaches the transition medium/support having a thickness/layer of 100-250 microns (Col. 9, line 49), but Schueller fails to teach:

- the thickness of the die being less than that of the transition medium; the thickness of the adhesive layers, transition medium and die is nearly equivalent to or same as the half of the package thickness, and
- a first and a second edge of the transition medium being coincident with those of the die respectively.

Zenner et al. teach using a high density/thin package having a die thickness of about less than 100 microns or preferably less than 20 microns and a package thickness of about 275 microns (Col. 2, line 15-22; Col. 3, line 55) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

Furthermore, the determination of parameters such as a thickness of a substrate/metallized polymer, plastic encapsulant/mold, finished package including the

die, substrate and the encapsulant, thickness/area/volume ratio of various components, relative position and an arrangement of various components within the package, etc. in the chip packaging and encapsulation technology art is a subject of routine experimentation and optimization to achieve the desired thermal, dimensional/mechanical and electrical/reliability requirements including weight/size, rigidity/strength and stress distribution.

Fukutomi et al. teach a BGA package (Fig. 17g) having dimensions of a flexible substrate, adhesive media, support/transition medium and a die (31/32, 36, 37 and 39 respectively in Fig. 17a-g) such that a first and a second edge of the support/transition medium are coincident with those of the die (see 37 and 39 respectively in Fig. 17e-g ; Col. 16, line 15- Col. 18, line 31), the adhesive media including the adhesive/bonding material above (not numerically referenced- see Col. 18, line 14) and below (see 36 in Fig. 18c-g) the support/transition medium (Col. 16, line 15- Col. 18, line 30).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the above elements as taught by Zenner et al. and Fukutomi et al. so that the thermal stress on the die due to thermal cycling or temperature extremes can be reduced, processing can be simplified and the package dimensions can be improved in Schueller's IC package.

7. Claims 49-59 and 61 are rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) in view of Zenner et al. (US Pat. 6246010) and Freyman et al. (US Pat. 5985695).

Regarding claim 49, Schueller discloses an integrated circuit (IC)/Ball Grid Array (BGA) package having a single or multiple IC dice (Fig. 3B; Col. 13, line 64), the package comprising:

- an IC die (52 in Fig. 3A) having a front side, backside and a first thickness between the front and back sides, where the bonding pads (Col. 8, line 25) are formed on the front side
- a metallized polymer layer/tape substrate (58/59/60 in Fig. 3A) having a first side and a second side wherein the bonding pads are electrically coupled to the features/patterns (59 in Fig. 3A) of the metallized polymer layer/tape using bonding wires (82A in Fig. 3A)
- a transition medium/support structure between the IC die and the metallized polymer layer (50A in Fig. 3A) having only an adhesive layer (64A in Fig. 3A) between the two where the transition medium/support structure has a second thickness, the second thickness being relatively uniform and none of the bonding pads being electrically coupled to the transition medium
- the transition medium/support structure comprising a variety of material including conventional PCB/a mold compound material such as an epoxy resin (Col. 10, lines 18-28)
- the backside of the IC die faces toward the transition medium and the front side of the IC die faces away from the metallized polymer layer/tape
- the IC die, metallized polymer layer/tape and transition medium are parallel planes, and
- solder balls (54 in Fig. 3A) below the metallized polymer layer/tape and the IC die electrically coupled to the bonding pads

(Fig. 3A; Col. 8, line 24; Col. 7, line 3- Col.1, line 12).

Schueller further teaches using a single transition medium/support structure having a second thickness/layer of 100-250 microns (Col. 9, line 49) or using a plurality of those layers (Col. 11, line 12) and the transition medium/support structure comprising the epoxy compound/mold compound material (Col. 10, line 18-27) but fails to teach:

a) the second thickness being greater than the first thickness, and
b) a first and a second edge of the transition medium being coincident with those of the silicon die respectively.

a) Zenner et al. teach using a high density/thin package having a die thickness of about less than 100 microns or preferably less than 20 microns and a package thickness of about 275 microns (Col. 2, line 15-22; Col. 3, line 55) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

b) Freyman et al. teach a BGA package (Fig. 7) having dimensions of a flexible substrate, an adhesive medium/transition and a die (201, 703 and 41 respectively in Fig. 7) such that a first and a second edge of the adhesive medium/transition medium are coincident with those of the die (see 703 and 41 respectively in Fig. 7; Col. 9, lines 1-5).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the second thickness of transition medium being greater than the first thickness as taught by Zenner et al. and the first and second edge of the transition medium being coincident with those of the silicon die respectively so that the thermal stress can be reduced, the functionality/reliability of the package can be improved and processing can be simplified in Schueller's IC package.

Regarding claim 50, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49, above, wherein Schueller teaches the front side of the die being faced away from the metallized polymer layer/tape (see Fig. 3A).

Regarding claim 51, Schueller and Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49, above, wherein Schueller teaches the IC die, metallized polymer layer/tape and transition medium being three parallel planes (see Fig. 3A).

Regarding claim 52, Schueller and Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49, above, wherein Schueller teaches the transition medium/support structure having a single/relatively uniform thickness (see Fig. 3A).

Regarding claim 53, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49, above, wherein Schueller further teaches the packages being sawed/diced into a single IC die/package (Col. 13, line 64).

Regarding claims 54 and 56, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49, above, wherein Schueller further teaches the bonding pads being electrically coupled to the features/patterns of the metallized polymer layer/tape using bonding wires (82A in Fig. 3A) and none of the bonding pads being electrically coupled to the transition medium.

Regarding claim 55, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49, above, wherein Schueller further teaches the transition medium/support comprising a single or multilayered structure including non-polymer material, ceramic or a combination of metal and non-metal/epoxy PCB material (Col. 9, line 58; Col. 10, line 27; Col. 11, line 12).

Regarding claim 57, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49 above, wherein Schueller further teaches having only an adhesive layer (64 in Fig. 3A) between the transition medium/support structure and IC die.

Regarding claim 58, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49 above, wherein Schueller teaches the back side of the die facing toward the transition medium (see Fig. 3A).

Regarding claim 59, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49 above, wherein Schueller teaches the IC package being the BGA package (see Fig. 3A).

Regarding claim 61, Schueller, Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 49 above, wherein Schueller further teaches the solder balls (54 in Fig. 3A) below the metallized polymer layer/tape and the IC die being electrically coupled to the bonding pads (Col. 8, line 25).

8. Claim 60 is rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949), Zenner et al. (US Pat. 6246010) and Freyman et al. (US Pat. 5985695) as applied to claim 49 above, and further in view of Lau (see "Chip on Board Technologies for Multichip Modules" edited by John H. Lau, published by Chapman & Hall, 1994).

Regarding claim 60, Schueller and Zenner et al. and Freyman et al. teach substantially the entire claimed structure as applied to claim 60 above, except the range of CTE for the transition medium being between $7 \times 10^{-6}/^{\circ}\text{C}$ and $17 \times 10^{-6}/^{\circ}\text{C}$.

Lau teaches the epoxy encapsulant/mold compound having the CTE from $10-15 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 474-476).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the transition medium having the CTE between $7 \times 10^{-6}/^{\circ}\text{C}$ and $17 \times 10^{-6}/^{\circ}\text{C}$ as taught by Lau so that the thermal stress can be reduced and the functionality/reliability can be improved Freyman et al., Zenner et al. and Schueller's IC package.

9. Claims 62, 64 and 67 are rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) in view of Zenner et al (US Pat. 6246010).

Regarding claim 62, Schueller discloses an integrated circuit (IC)/BGA package comprising:

- a silicon die (52 in Fig. 3A) having a first thickness
- a substrate comprising a metallized polymer layer/tape (59/60 in Fig. 3A; Col. 7, line 30) having a first/top side and a second/bottom side, and
- a transition medium/support structure (50 in Fig. 3A) disposed between the silicon die and the substrate, the transition medium/support structure having a second thickness, the transition medium/support structure comprising a variety of material including conventional PCB/a first mold compound material such as an epoxy resin (Col. 10, lines 18-28)
- a conventional plastic encapsulant/epoxy resin/mold cap encapsulating the die and the transition medium (mold cap not numerically referenced- see Fig. 3A; Col. 8, line 40),
- the mold cap/epoxy resin/encapsulant/first mold compound and the transition medium/support structure/first mold compound material comprising the epoxy resin material having a similar/approximately equal CTE

(Fig. 3A; Col. 7, line 15- Col. 10, line 36; Col. 5, line 36- Col. 6, line 55).

Schueller teaches the transition medium/support and the encapsulant comprising the first mold compound/epoxy resin having approximately same CTE and further teaches

the transition medium/support having a thickness/layer of 100-250 microns (Col. 9, line 49) and being made of PCB/FR-4 type material (Col. 10, line 18-27).

Schueller fails to teach the thickness of the transition medium being greater than that of the die.

Zenner et al. teach using a high density/thin package having a die thickness of about less than 100 microns or preferably less than 20 microns and a package thickness of about 275 microns (Col. 2, line 15-22; Col. 3, line 55) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to select the thickness of the transition medium being greater than that of the die and the transition medium as taught by Zenner et al. so that the thermal stress can be reduced and the functionality/reliability of the package can be improved in Schueller's IC package.

Regarding claim 64, Schueller, and Zenner et al. teach substantially the entire claimed structure as applied to claim 62 above, wherein Schueller further teaches the distance from the top of the plastic encapsulant/mold cap being the package thickness, wherein the die is positioned approximately in the middle of the package thickness (see Fig. 3B).

Furthermore, the determination of parameters such as a thickness of a substrate/metallized polymer, plastic encapsulant/mold, finished package including the

die, substrate and the encapsulant, thickness/area/volume ratio of various components, relative position and an arrangement of various components within the package, etc. in the chip packaging and encapsulation technology art is a subject of routine experimentation and optimization to achieve the desired thermal, dimensional/mechanical and electrical/reliability requirements including weight/size, rigidity/strength and stress distribution.

Regarding claim 67, Schueller, and Zenner et al. teach substantially the entire claimed structure as applied to claim 62 above.

10. Claim 63 is rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) and Zenner et al (US Pat. 6246010) as applied to claim 62 above, and further in view of Fukutomi et al. (US Pat. 5796912).

Regarding claim 63, Schueller and Zenner et al. teach substantially the entire claimed structure as applied to claim 62 above, except a first and a second edge of the transition medium being coincident with those of the die

Fukutomi et al. teach a BGA package (Fig. 17g) having dimensions of a flexible substrate, adhesive media, support/transition medium and a die (31/32, 36, 37 and 39 respectively in Fig. 17a-g) such that a first and a second edge of the support/transition medium are coincident with those of the die (see 37 and 39 respectively in Fig. 17e-g ; Col. 16, line 15- Col. 18, line 31), the adhesive media including the adhesive/bonding material above (not numerically referenced- see Col. 18,

line 14) and below (see 36 in Fig. 18c-g) the support/transition medium (Col. 16, line 15-Col. 18, line 30).

11. Claims 66 and 68 are rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) and Zenner et al (US Pat. 6246010) as applied to claims 62 and 67 respectively above, and further in view of Lau (see "Chip on Board Technologies for Multichip Modules" edited by John H. Lau, published by Chapman & Hall, 1994).

Regarding claim 66, Schueller and Zenner et al. teach substantially the entire claimed structure as applied to claim 62 above, except the range of CTE for the transition medium being between $7 \times 10^{-6}/^{\circ}\text{C}$ and $17 \times 10^{-6}/^{\circ}\text{C}$.

Schueller further teaches the transition medium/support structure being made of PCB/FR-4 type material (Col. 10, line 18-27).

Lau teaches a conventional PCB/FR-4 material having a CTE ranging from $5-19 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 52, Table 1-7).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the transition medium having the CTE between $7 \times 10^{-6}/^{\circ}\text{C}$ and $17 \times 10^{-6}/^{\circ}\text{C}$ as taught by Lau so that the thermal stress can be reduced and the functionality/reliability can be improved Zenner et al. and Schueller's IC package.

Regarding claim 68, Schueller and Zenner et al. teach substantially the entire claimed structure as applied to claim 67 above, except the CTE of the transition medium being greater than that of the silicon die.

Lau teaches a conventional silicon die being $2.5-3.0 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 52) and a PCB/FR-4 material having a CTE ranging from $5-19 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 52, Table 1-7).

It would have been obvious to a person of ordinary skill in the art at the time invention was made to incorporate the transition medium being greater than that of the silicon die as taught by Lau so that the thermal stress can be reduced and the functionality/reliability can be improved Zenner et al. and Schueller's IC package.

12. Claim 69 is rejected under 35 U.S.C. 103(a) as being unpatentable over Schueller (US Pat. 5866949) in view of Zenner et al. (US Pat. 6246010), Fukutomi et al. (US Pat. 5796912) and Lau (see "Chip on Board Technologies for Multichip Modules" edited by John H. Lau, published by Chapman & Hall, 1994).

Regarding claim 69, Schueller discloses an integrated circuit (IC)/BGA package comprising:

- a silicon die (52 in Fig. 3A) having a first thickness
- a metallized polymer layer (MPL)/tape substrate (59/60 in Fig. 3A; Col. 7, line 30) having a first/top side and a second/bottom side, and
- a transition medium/support structure (50 in Fig. 3A) disposed between the silicon die and the MPL, the transition medium/support structure having a second thickness, and

- the package having external connections/solder balls (54 in Fig. 3A) and being capable of being mounted to a printed circuit board (PCB) (Fig. 3A; Col. 7, line 15- Col. 10, line 36; Col. 5, line 36- Col. 6, line 55).

Schueller further teaches the transition medium/support structure comprising the epoxy compound/mold material (Col. 10, line 18-27) and the transition medium/support having a thickness/layer of 100-250 microns (Col. 9, line 49).

Schueller fails to teach:

a) the first thickness of the die being less than the second thickness and a first and a second edge of the transition medium being coincident with those of the die respectively, and
b) both the transition medium and the encapsulant having a CTE being less than the PCB and being greater than that of the silicon die.

a) Zenner et al. teach using a high density/thin package having a die thickness of about less than 100 microns or preferably less than 20 microns and a package thickness of about 275 microns (Col. 2, line 15-22; Col. 3, line 55) to reduce the total volume of the package, thermal stress, stress related failures and to improve functionality/reliability due to the thermal expansion mismatch (Col. 4, line 55- Col. 5, line 20).

Fukutomi et al. teach a BGA package (Fig. 17g) having dimensions of a flexible substrate, adhesive media, support/transition medium and a die (31/32, 36, 37 and 39 respectively in Fig. 17a-g) such that a first and a second edge of the support/transition

medium are coincident with those of the die (see 37 and 39 respectively in Fig. 17e-g ; Col. 16, line 15- Col. 18, line 31), the adhesive media including the adhesive/bonding material above (not numerically referenced- see Col. 18, line 14) and below (see 36 in Fig. 18c-g) the support/transition medium (Col. 16, line 15- Col. 18, line 30).

b) Lau teaches a conventional silicon die having a CTE of $2.5-3.0 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 52), conventional PCB having that from $5-19 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 52, Table 1-7) and an epoxy encapsulant/mold compound having that from $10-15 \times 10^{-6}/^{\circ}\text{C}$ (see pp. 474-476), such that one or more values from these ranges can be selected to satisfy the requirement for the transition medium having the CTE being greater than that of the silicon die and less than that of the PCB.

Furthermore, the determination of parameters such as a thickness of a substrate/metallized polymer, plastic encapsulant/mold, finished package including the die, substrate and the encapsulant, thickness/area/volume ratio and CTE/composition of various components in the chip packaging and encapsulation technology art is a subject of routine experimentation and optimization to achieve the desired thermal, dimensional/mechanical and electrical/reliability requirements including weight/size, rigidity/strength and stress reduction due to thermal mismatch.

It would have been obvious to a person of ordinary skill in the art at the time invention was made to select the first thickness of the die being less than the second thickness, the first and second edge of the transition medium being coincident with those of the die respectively and both the transition medium and the encapsulant having a CTE being less than the PCB and being greater than that of the silicon die as taught by Lau, Zenner et al., Fukutomi al. and APA so that the thermal stress can be reduced,

the functionality/reliability of the package can be improved and processing can be simplified in Schueller's IC package.

Response to Arguments

13 A. Transition Medium/CTE Related:

Applicant's arguments with respect to the above have been considered but are moot in view of the new ground(s) of rejection.

B. Applicant contends that none of the references teach the first thickness of the silicon die being less than the second thickness.

However, as explained above, Schueller further teaches using the transition medium/support structure having a second thickness/layer of 100-250 microns (Col. 9, line 49). Zenner et al. teach using the die thickness of about less than 100 microns or preferably less than 20 microns (Col. 2, line 15-22; Col. 3, line 55). Therefore, the combination of Schueller and Zenner et al. teach the claimed limitations.

Conclusion

14 **THIS ACTION IS MADE FINAL.** Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Nitin Parekh whose telephone number is 571-272-1663. The examiner can normally be reached on 09:00AM-05:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eddie Lee can be reached on 571-272-1732. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9318.

Art Unit: 2811

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

NP

03-09-05



NITIN PAREKH

PRIMARY EXAMINER

TECHNOLOGY CENTER 2800